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**RESPONSE TO OFFICE ACTION
UNDER 37 CFR 1.116 EXPEDITED
PROCEDURE - EXAMINING GROUP
1763**

Box AF
Assistant Commissioner for Patents
Washington, D.C. 20231

On July 2, 2002

TOWNSEND and TOWNSEND and CREW LLP

By: Andrew

PATENT

Attorney Docket No.: 1084D01T93200
TTC No.: 16301-009320

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

David Cheung et al.

Application No.: 09/418,818

Filed: October 15, 1999

For: METHOD AND APPARATUS FOR
DEPOSITING ANTIREFLECTIVE
COATING

Examiner: Rudy Zervigon

**RESPONSE TO OFFICE ACTION UNDER
37 CFR 1.116 EXPEDITED PROCEDURE
EXAMINING GROUP 1763**

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Box AF
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Washington, D.C. 20231

Sir:

In response to the Final Office Action mailed May 2, 2002, please reconsider this application in view of the following comments.

IN THE CLAIMS:

The claims are unamended, but are reproduced below for the Examiner's convenience and reference.

1. A substrate processing system, comprising:
a vacuum chamber;